



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Atsushi YAMAGUCHI et al.

Application No.: 10/022,228

Filed: December 20, 2001

For: EXPOSURE APPARATUS AND EXPOSURE METHOD

Group Art Unit: 2851

Examiner: H. Nguyen

Docket No.: 111476

#12/B  
3-27-03  
JFC

AMENDMENT

Director of the U.S. Patent and Trademark Office  
Washington, D.C. 20231

Sir:

In reply to the September 20, 2002, Office Action, the shortened statutory period for reply being extended by the attached Petition for Extension of Time, please amend the above-identified application as follows:

IN THE DRAWINGS:

Please amend Figure 1 as set forth in the attached Request for Approval of Drawing Corrections.

IN THE SPECIFICATION:

Please replace paragraph [0064] as follows:

[0064] Above, an example of the processing for finding the range of acceleration where offset of the reticle R will not occur when causing the reticle stage 11 to accelerate was explained, but similar processing may be performed to derive by a process of trial and error the range of acceleration where offset of the reticle R will not occur when causing the reticle stage 11 to decelerate. At this time, it is sufficient to find the ranges of acceleration in accordance with the directions of movement (for example, forward direction and reverse

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